

**INSPECTION TOOL WITH A 3D POINT SENSOR TO DEVELOP A
FOCUS MAP**

Abstract of the Disclosure

- 5 An inspection system, and process for use thereof, allows for inspecting of semiconductors or like substrates. The inspection system keeps the focus of the sensor within the depth of field of the lens used. The system specifically uses the process of making a separate pass over the wafer surface using a 3D point sensor before the inspection of the wafer begins.
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